

TABLE OF CONTENTS

1.	Scope	2
2.	Applicable Documents.....	2
3.	Order Requirements	2
4.	Processing Overview	2
5.	Substrate Material	3
5.1.	Alumina As Fired	3
5.2.	Alumina Polished	4
5.3.	Fused Silica	4
5.4.	Optimum Finished Substrate Dimensions	4
6.	Metalization.....	6
7.	Conductor Patterns	6
7.1.	Minimum Line Width.....	6
7.2.	Minimum Gap	6
7.3.	Fabrication Process.....	7
7.3.1.	Etch Back Process.....	7
7.3.2.	Pattern Plate Process	7
7.4.	Etch Factor	8
7.5.	Trace to Edge of Substrate.....	9
7.6.	Avoid Acute Angles.....	9
8.	Resistor Patterns.....	9
8.1.	Minimum Resistor Dimension	9
8.2.	Resistor Values.....	9
8.3.	Small Critical Resistors	10
8.4.	Resistor Accuracy.....	10
8.5.	Laser Trimming.....	10
8.5.1.	Plunge Cut	11
8.5.2.	L Cut	11
8.5.3.	Edge-Trim.....	11
8.5.4.	Center-Trim.....	11
8.6.	Combining Laser and Non-Laser Trimmed Resistors on One Substrate	11
9.	Overlap of Resistors and Gold	12
10.	Gold Trace Larger than Resistor	13
11.	Power Dissipation	13
12.	Vias, Slots and Laser Notch / Post Cut	13
12.1.	Via Diameter	13
12.2.	Pad Size for Vias.....	13
12.3.	Distance from Edge of Via to Edge of Substrate	14
12.4.	Distance between Vias.....	14
12.5.	Vias in a Line.....	14
12.6.	Slots	14
13.	Double Sided Circuits	14
13.1.	Front to Back Alignment	14
14.	Step and Repeating and Alignment Marks	14
15.	Integrated Capacitors	14
15.1.	General	14
15.2.	Film Properties	14
15.3.	Applications	15
15.3.1.	Capacitor.....	15
15.3.2.	Top Metal	15
15.3.3.	Connection.....	15
15.4.	Overlay Coupler	15
15.5.	Solder Dam	17

1. Scope

This document is intended to provide a guide to designers of thin film substrates. The guide is intended to document the substrate features that can be reliably and economically fabricated in Anritsu's Microwave Technology Center (MTC). In many cases, the limits stated herein represent features that have been successfully produced in the past, rather than a fundamental limit on the capabilities of a given process. As more definitive data is obtained on the processes, this procedure will be updated accordingly.

If a designer is able to produce a working design within the limits of this document, he can count on obtaining quality substrates. If the particular needs of a given design fall outside of these limits, the designer should discuss these needs with MTC personnel. It may be possible for the MTC to develop a new process or refine an existing process to achieve the desired result. It also may be decided that the existing processes can support the design even with low yields.

2. Applicable Documents

MTC-102 Guidelines for Mask Design

MTC-103 MTC Standard Notes

MTC Circuit Request Form

3. Circuit Order Requirements

- Please fill out the MTC Circuit Request Form
- DXF or DWG CAD drawings with different layers clearly marked is helpful. Do not array or add any ETCH BIAS factor to circuit dimensions. MTC personnel can also help with the CAD drawing if needed.
- Consult with MTC Fab personnel if you have any questions or if the Design Guide does not cover your design needs.

4. Processing Overview

In order to produce thin film MIC circuits, the following steps are performed. These steps are somewhat simplified. Consult MTC if more detail is desired.

- Substrate Blanks are purchased
- Blanks are laser drilled (if applicable)
- Tantalum Nitride is sputtered onto the substrate (if applicable)
- Titanium Tungsten is sputtered onto the substrate. Other adhesion or barrier metal layers can then be sputtered if needed. Examples include Nickel, Palladium and Chromium.
- Gold is sputtered and plated onto the substrate
- Photoresist is spun onto the substrate
- Photolithography transfers the pattern from the mask to the photoresist
- Gold is etched away where not desired to form the conductor patterns if using etch back process OR gold is plated in areas desired to form the conductor patterns if using pattern plate process
- Exposed Titanium Tungsten is etched away
- Photolithography transfers the pattern from the mask to the photoresist
- Tantalum Nitride is etched away where not desired to form resistors
- Resistors are heat treated to stabilize the values
- An adhesion layer of Titanium is deposited (capacitors and solder dams only)
- Polyimide is spun onto the substrate (capacitors and solder dams only)
- Polyimide is patterned and cured (capacitors and solder dams only)
- Top metal seed layer (Titanium – Titanium Tungsten -Gold) is deposited (capacitors only)

- Top metal is patterned by using pattern plate process (capacitors only)
- Resistors are either heat treated to final value or laser trimmed as specified
- Substrates are laser notched (post cut), if applicable
- Substrates are sawed into their final dimensions

5. Substrate Material

A variety of substrate materials have been patterned successfully, although the most common material used in the Fab currently is Alumina (Al₂O₃). The standard alumina (Al₂O₃) substrates come in two forms, As Fired and Polished, and both forms are available in a variety of thicknesses. The common substrate thickness is shown in the Table below. As Fired substrates have looser tolerances and rougher surface finishes, which makes it more difficult to hold tight tolerances on line widths and resistor values. Also, since the thickness tolerance is larger, even a line with a tight tolerance may not have the exact impedance desired. However, As-Fired material is cheaper and available in larger sizes, thus, if no critical features are required, it should be used. Metal adhesion to As-Fired surfaces is also better than to polished surfaces. MTC reserves the right to use polished substrates in place of As-Fired at their discretion. On the other hand, As-Fired substrates will not be used in place of polished substrates without the designer's approval.

Other types of substrate material that MTC processes regularly include alumina nitride, fused silica and polished sapphire. The MTC Fab stock many types of substrates, and will assist in procuring material not in stock. Other materials like Silicon, quartz, CVD Diamond, BeO and other more exotic materials also have been successfully processed in the Fab. The following table shows the substrate material properties of some common materials.

Substrate Material Properties

Material	CLA Surface Roughness (μ-inches)	Thickness Tolerance (inches)	Dissipation Factor at (1kHz) / 1MHz	Dielectric Constant (k)	Thermal Conductivity (W/mK)	Thermal Expansion (μ"/inch/ °C)
As Fired 99.6% Alumina	A-side < 2 B-side < 3	Depend on thickness	(.0003) / .0001	9.9 ± 0.1	30	7.1
Polished 99.6% Alumina	< 0.5		.0001	9.9 ± 0.1	30	7.1
Aluminum Nitride *	8-24	± 5%	0.001	8.6	170	4.6
Fused Silica *	7	± 5%	.000015	3.8	1	.55
Polished Sapphire *	1.0	± 5%	0.0086	11.5	N/A	5.3

* Material Properties may vary depend on manufacturer and surface finish

5.1. Alumina As Fired

The following table shows some of the sizes and thicknesses of Alumina As-Fired substrates that we have on hand.

Thickness (inch)	Thickness Tolerance (inch)	Size (inch)	Part Number
.005	± .0005	2.00 x 2.00	704-34
.010	± .0005	1.00 x 1.00	704-35
		2.00 x 2.00	704-31
		3.25 x 3.25	704-61
.015	± .00075	1.00 x 1.00	704-36
		2.00 x 2.00	704-32
		3.25 x 3.25	704-62
.025	± .00125	1.00 x 1.00	704-37

		2.00 x 2.00	704-33
		3.25 x 3.25	704-63

5.2. Alumina Polished

The following table shows all the different sizes and thicknesses of Alumina Polished substrates that we have on hand.

Thickness (inch)	Thickness Tolerance (inch)	Size (inch)	Part Number
.003	± .0002	1.00 x 1.00	704-64*
.005	± .0002	1.00 x 1.00	704-46
		2.00 x 2.00	704-85
.006	± .0002	1.00 x 1.00	704-59*
.0075	± .0001	2.00 x 2.00	704-75*
.010	± .0001	2.00 x 2.00	704-43
	± .0002	3.25 x 3.25	704-86
.015	± .0002	2.00 x 2.00	704-44
		3.25 x 3.25	704-87
.025	± .0004	2.00 x 2.00	704-45
	± .0005	3.25 x 3.25	704-88

* These substrates are available but are non-standard and should not be used unless absolutely necessary

5.3. Fused Silica

Thickness (inch)	Thickness Tolerance (inch)	Size (inch)	Part Number
.005	± .0002	1.00 x 1.00	704-69

5.4. Optimum Finished Substrate Dimensions

In order to minimize the cost per substrate, it is best if the substrate dimensions maximize the number of finished substrates per substrate blank. The most common width of the saw blade, known as saw kerf, is 10 mil, although 4 mil, 6 mil, 8 mil and 20 mil wide blades may be used. MTC requires a minimum of 75 mil border (exclusion border) around the edge of the substrates for handling. Therefore, the maximum size for a given number of rows or columns that can be fabricated on a substrate is calculated as follows:

$$MaximumDimension^* = \frac{[(Size\ of\ Substrate\ Blank) - (2 \times Border) - SawKerf(N - 1)]}{N}$$

* Round down to nearest mm

Where Size of substrate blank \cong 82.5 (for 3.25") or 50.8 (for 2.00") or 25.4 (for 1.00") mm

Border \cong 2 mm (for 3.25" & 2.00") or 1.5 mm (for 1.00")

Saw Kerf \cong .26 mm (for 0.010") or .52 mm (for 0.020")

N is the number of rows and/or columns

Maximum Number of Finished circuit

The following tables can be used to estimate the maximum number of finished circuit for 3.25" x 3.25", 2.00" x 2.00" and 1.00" x 1.00" substrate, respectively. If the finished substrate 'X' dimension is equal to or less than the dimension in the top row below and if your finished substrate 'Y' dimension is equal to or less than the dimension in the left column below, then the number at the intersection of that row and column is the maximum number of finished circuits that can be yielded from the substrate blank.

3.25" x 3.25" Substrate Blank

	76.00	37.87	25.16	18.81	14.99	12.45	10.63	9.27	8.21	7.37	6.67	6.10	5.61	5.19
76.00	1	2	3	4	5	6	7	8	9	10	11	12	13	14
37.87	2	4	6	8	10	12	14	16	18	20	22	24	26	28
25.16	3	6	9	12	15	18	21	24	27	30	33	36	39	42
18.81	4	8	12	16	20	24	28	32	36	40	44	48	52	56
14.99	5	10	15	20	25	30	35	40	45	50	55	60	65	70
12.45	6	12	18	24	30	36	42	48	54	60	66	72	78	84
10.63	7	14	21	28	35	42	49	56	63	70	77	84	91	98
9.27	8	16	24	32	40	48	56	64	72	80	88	96	104	112
8.21	9	18	27	36	45	54	63	72	81	90	99	108	117	126
7.37	10	20	30	40	50	60	70	80	90	100	110	120	130	140
6.67	11	22	33	44	55	66	77	88	99	110	121	132	143	154
6.10	12	24	36	48	60	72	84	96	108	120	132	144	156	168
5.61	13	26	39	52	65	78	91	104	117	130	143	156	169	182
5.19	14	28	42	56	70	84	98	112	126	140	154	168	182	196

2.00" x 2.00" Substrate Blank

	44.00	21.87	14.49	10.81	8.59	7.12	6.06	5.27	4.66	4.17	3.76	3.43	3.14	2.90
44.00	1	2	3	4	5	6	7	8	9	10	11	12	13	14
21.87	2	4	6	8	10	12	14	16	18	20	22	24	26	28
14.49	3	6	9	12	15	18	21	24	27	30	33	36	39	42
10.81	4	8	12	16	20	24	28	32	36	40	44	48	52	56
8.59	5	10	15	20	25	30	35	40	45	50	55	60	65	70
7.12	6	12	18	24	30	36	42	48	54	60	66	72	78	84
6.06	7	14	21	28	35	42	49	56	63	70	77	84	91	98
5.27	8	16	24	32	40	48	56	64	72	80	88	96	104	112
4.66	9	18	27	36	45	54	63	72	81	90	99	108	117	126
4.17	10	20	30	40	50	60	70	80	90	100	110	120	130	140
3.76	11	22	33	44	55	66	77	88	99	110	121	132	143	154
3.43	12	24	36	48	60	72	84	96	108	120	132	144	156	168
3.14	13	26	39	52	65	78	91	104	117	130	143	156	169	182
2.90	14	28	42	56	70	84	98	112	126	140	154	168	182	196

1.00" x 1.00" Substrate Blank

In the case of 1.00" x 1.00" substrate blanks, MTC has reduced their border for handling from 3 mm to 1.5 mm. This allows for more substrates per substrate blank; however, some of the substrates near the edge are likely to be damaged by handling.

	22.00	10.87	7.16	5.31	4.19	3.45	2.92	2.52	2.21	1.97	1.76	1.60	1.45	1.33
22.00	1	2	3	4	5	6	7	8	9	10	11	12	13	14
10.87	2	4	6	8	10	12	14	16	18	20	22	24	26	28
7.16	3	6	9	12	15	18	21	24	27	30	33	36	39	42
5.31	4	8	12	16	20	24	28	32	36	40	44	48	52	56
4.19	5	10	15	20	25	30	35	40	45	50	55	60	65	70
3.45	6	12	18	24	30	36	42	48	54	60	66	72	78	84
2.92	7	14	21	28	35	42	49	56	63	70	77	84	91	98
2.52	8	16	24	32	40	48	56	64	72	80	88	96	104	112
2.21	9	18	27	36	45	54	63	72	81	90	99	108	117	126
1.97	10	20	30	40	50	60	70	80	90	100	110	120	130	140

1.76	11	22	33	44	55	66	77	88	99	110	121	132	143	154
1.60	12	24	36	48	60	72	84	96	108	120	132	144	156	168
1.45	13	26	39	52	65	78	91	104	117	130	143	156	169	182
1.33	14	28	42	56	70	84	98	112	126	140	154	168	182	196

Metallization

The following table is the summary of some common MTC metals. Other metals are available for development type of circuits.

Material Function	Types of Material	Thickness / Values
Resistor	Tantalum-Nitride (TaN)	Standard: 50 and 100 Ω / sq. Non-standard: 10 – 200 Ω / sq.
Adhesion	Titanium-Tungsten (TiW)	1000 Angstroms
Adhesion	Titanium	1000 Angstroms
Adhesion	Chromium	1000 Angstroms
Barrier	Nickel	2000 Angstroms
Barrier	Palladium	2000 Angstroms
Conductor	Gold (Au)	Standard: 2.5, 5.0 μ m
Conductor	Palladium (Pd)	Standard: 0.5 μ m to 2.0 μ m

The most common basic metallization scheme for thin film substrates contains Titanium – Tungsten (TiW) and Gold (Au). Tantalum Nitride (TaN) is only sputtered if there is a resistor design in the substrates. A range of sheet resistance is possible. Two values, 50 Ω / sq. and 100 Ω / sq. are the Anritsu standards. Resistors formed of this material require heat treating for stability. Generally, the Tantalum-Nitride is sputtered about 20% lower in sheet resistivity than the final desired value. Usually the designer does not need to worry about this process since only the final resistivity is important. The exception occurs with the introduction of laser trimming, especially if there are laser and non-laser trimmed resistors on one substrate, more thought must be put into the design of the resistors. This will be discussed further in the resistor section of this guide. Titanium – Tungsten (TiW) is used as a diffusion barrier layer, while gold is the standard conductor metal at Anritsu. The gold thickness standard is 2.5 μ m. For devices needing the use of solders that may leach gold, a Palladium or Nickel layer can be used underneath the Gold layer. Other metallization schemes (involving Copper, Nickel etc) can be fabricated. Please consult with MTC personnel.

6. Conductor Patterns

6.1. Minimum Line Width

The narrowest line width attainable is 5 μ m with a tolerance of \pm 10% using a Contact Aligner.

A Canon Stepper can also be used sometimes to achieve narrower line widths. Consult MTC personnel.

6.2. Minimum Gap

The narrowest gap attainable is 5 μ m standard* with a tolerance of \pm 10%

A Canon Stepper can also be used sometimes to achieve narrower gap widths. Consult MTC personnel.

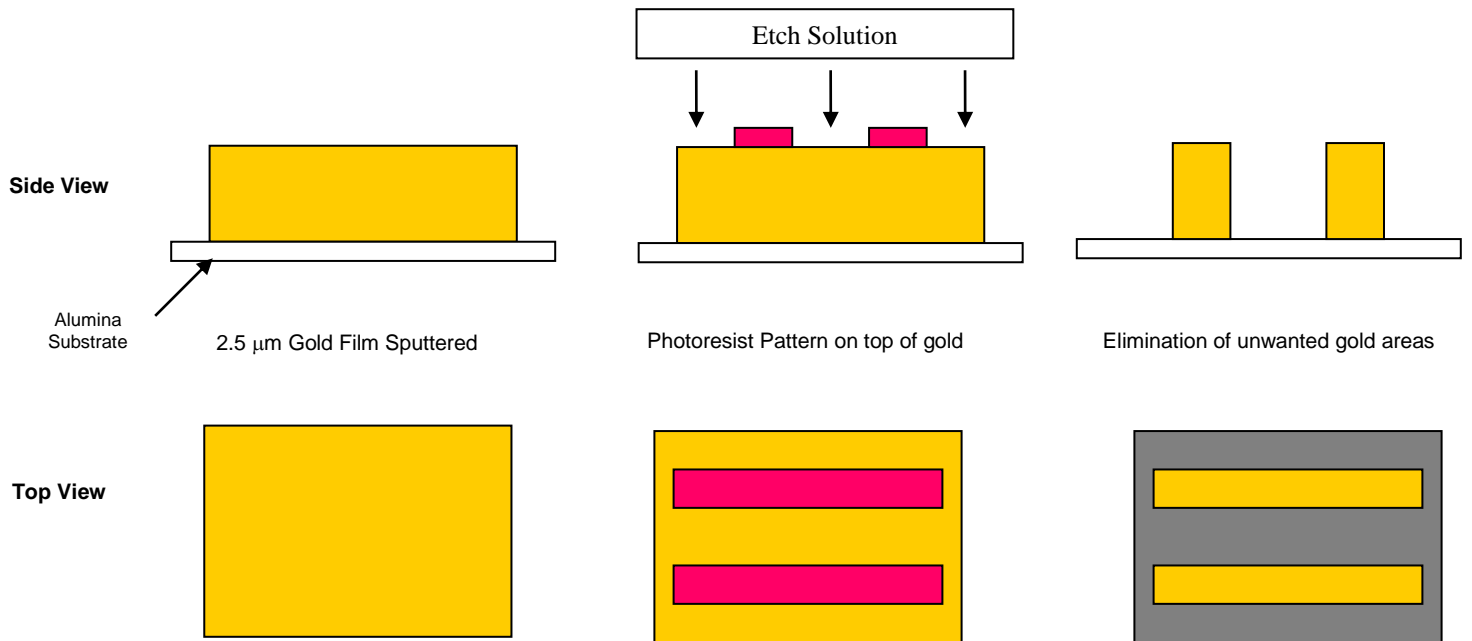
*MTC will attempt to fabricate substrates with narrower line and / or gap widths, as device performance necessitate the use of smaller and smaller dimensions. Please consult with MTC personnel to come up with suitable process flows to achieve the needed dimensions.

6.3. Fabrication Process

There are two different processes used to fabricate the conductor patterns; an etch-back process or a selective pattern plate process. The etch-back process is currently the standard process used in MTC. It is generally the preferred method, as the metal adhesion is best. However, when the design involves numerous via holes and slots features, a selective plate process may be needed. The Fab engineering staff will be available to help customer design the best fabrication flow to achieve the device designs.

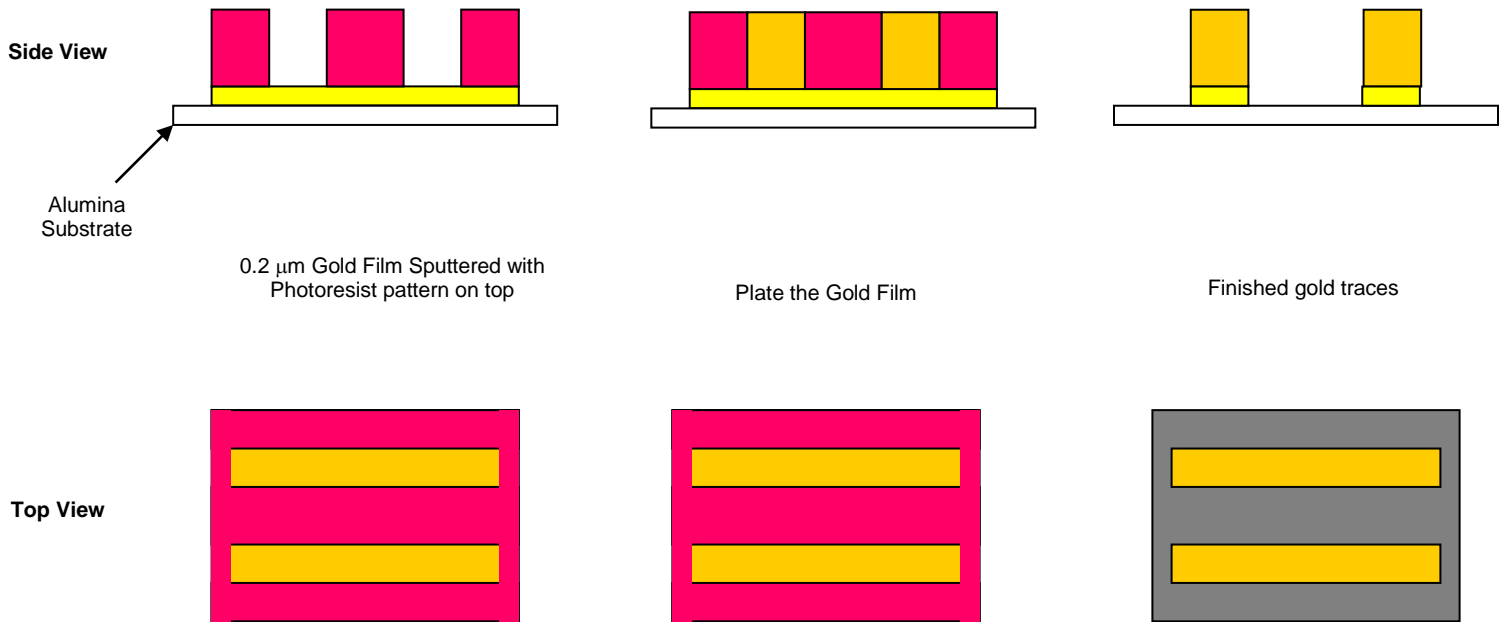
6.3.1. Etch Back Process

Etch back process forms the conductor pattern by selectively etching gold away from a substrate through a photoresist mask layer. The conductor pattern is protected by the photoresist during the etching process. The gold traces formed are slightly smaller, because of the existence of etch factor than the photoresist trace.



6.3.2. Pattern Plate Process

Pattern Plate process creates a pattern by selectively gold plating a substrate through a photoresist mask layer. The etch factor is smaller compare to the etch back process since the plating is constrained by the photoresist walls.



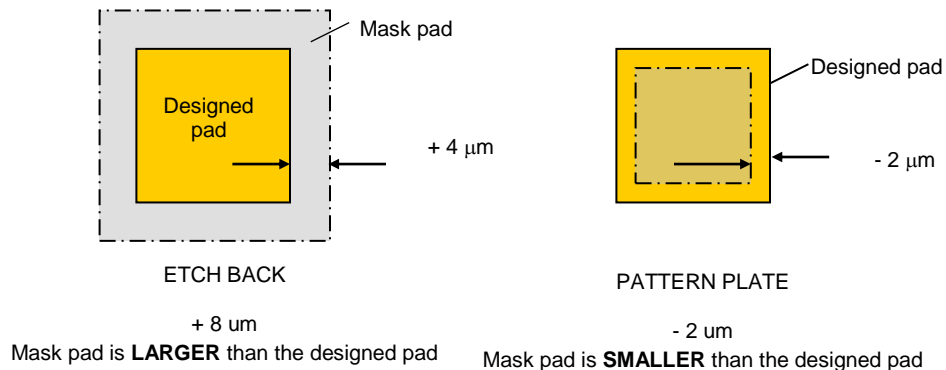
6.4. Etch Factor

Since the two processes work on the opposite way to each other, different etch factor should also be applied. For etch back process, lines become narrower and gaps become larger than the dimensions on the mask. For critical dimension, an etch factor should therefore be designed into the artwork. For designs with a standard 2.5 μm of metal, a patterned line width will decrease by 8 μm and the corresponding gap width will increase by 8 μm . For example, a Lange coupler with line widths of 30 μm and gaps of 25 μm are desired. The mask should be designed with line widths of 38 μm and gaps of 17 μm to achieve the desired dimensions.

Conversely, for the pattern plate process, line become wider and gaps becomes narrower. In the example of Lange Coupler, the mask should be designed with line widths of 26 μm and gaps of 29 μm to achieve the desired dimensions. For resistors with critical tolerances and small physical size, this etch factor should also be applied to the gold conductors forming the gap which the resistor will bridge.

The following table shows both of the etch factor. Be careful with the difference sign of the etch factor. The diagram below the table will help explain the difference.

Type of process	Etch Factor (both sides)
Etch back	+ 8 μm / 0.0003" / 0.3 mil
Pattern Plate	- 4 μm / 0.00015" / 0.15 mil



6.5. Trace to Edge Circuit

During the substrate sawing process, there is a significant possibility that substrate metallization will peel if the saw goes through a metalized portion of the circuit. Therefore, a minimum of 0.03 mm should be left between the metal trace and the edge of the circuit. The preferred margin is 0.05 mm.

6.6. Avoid Acute Angles

In the mask creation process, the patterns are formed on the mask using rectangular flashes of light. Certain patterns, especially acute angles, require numerous flashes to form. This can result in over exposure and bleed out in these areas of the mask.

7. Resistor Patterns

7.1. Minimum Resistor Dimension

Resistor dimension widths and length should be larger than .025 mm (1 mil), although smaller resistor dimensions are possible. Consult with MTC personnel.

7.2. Resistor Values

The resistors used at Anritsu are normally formed from one of two standard sheet resistivity, which are 50 Ω/sq . and 100 Ω/sq . The value of a resistor element is calculated as follows:

$$R = \frac{L \times R_s}{W}$$

Where L = Length of Resistor
W = Width of Resistor
Rs = Sheet Resistivity (either 50 or 100 Ω / square)

7.3. Small Critical Resistors

When the value of a physically small resistor is important, remember to apply the etch factor to the gold traces that form the ends of the resistor.

7.4. Resistor Accuracy

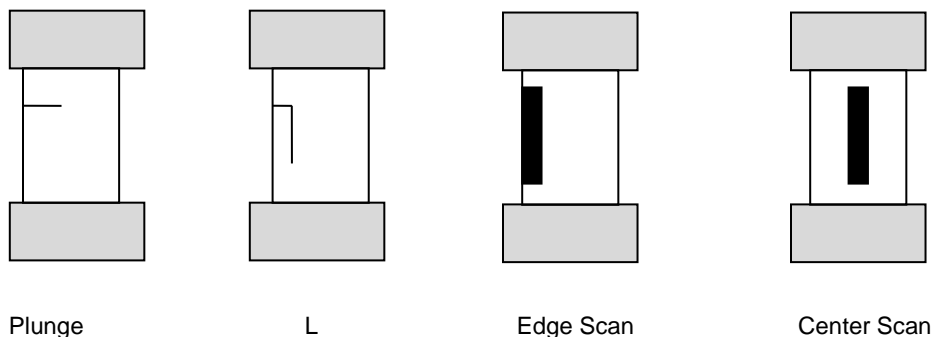
Resistors must be heat treated in order to be stable over time. Heat treating causes the value of a resistor to increase. Typically the resistive layer is sputtered on at approximately 80% of the final desired sheet resistivity and then the patterned substrate is heat treated until a test resistor (or other resistor identified on the drawing as critical) is measured as being within 10% of its design value. For high accuracy resistors, etched resistors can be laser trimmed to tight tolerances after a minimum amount of heat treating has been performed. For laser trimmed resistors, we will heat treat the resistors to within a minimum of 80% of the nominal value, and laser trim to specs. Therefore, we will not trim more than 20% of the resistor value away.

Standard Resistor Accuracy – No Laser Trimming	
Test Resistor (or critical resistor)	10%
Other Resistors	10%

Laser Trimmed Resistors	
Standard	1%
Special	0.1%

7.5. Laser Trimming

There are four types of laser trimming patterns that can be specified: plunge, L, edge-trim and center trim. These are illustrated below:



7.5.1. Plunge Cut

This cut is the quickest and easiest cut for the laser system to make. It is therefore the cheapest. Accuracy of 1% is achievable. The maximum allowable cut is 50% of the resistor width. This can seriously affect the power handling capability of the resistor. Also, it does not result in a good RF match. This type of cut is best suited for reasonably high accuracy DC resistors with plenty of excess power handling capability.

7.5.2. L Cut

This cut is similar to the plunge cut, but allows for higher accuracy. It is a little more expensive than the plunge cut. Accuracy of 0.1% is achievable. The first part of the cut is a plunge. This changes the resistor value quickly. Again, the maximum allowable plunge is 50% of the resistor width. This can seriously affect the power handling capability of the resistor. Also, it does not result in a good RF match. The perpendicular cut changes the resistor value very slowly, thus making high accuracy possible. This type of cut is best suited for very high accuracy DC resistors with plenty of excess power handling capability.

7.5.3. Edge-Trim

This cut is made by trimming very slowly on the entire edge of a resistor. It is much more time consuming than the plunge or L cut. Accuracy of 0.1% is achievable. The same 50% of resistor width maximum cut applies. However, this cut generally results in much less narrowing of the resistor than the first two cuts. This means that the power handling ability of the resistor is less compromised. Also, RF performance is better than either of the first two cuts. This type of cut is best suited for very high accuracy DC resistors with more marginal power handling capability or RF resistors with moderate performance.

7.5.4. Center-Trim

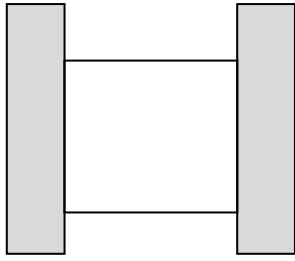
This cut is made by slowly trimming from the center of a resistor. It is the most time consuming trim performed and therefore the most expensive. The same 50% of resistor width maximum cut applies. However, this cut generally results in much less narrowing of the resistor than the first two cuts. This means that the power handling ability of the resistor is less compromised. This type of cut may give the best RF performance of any of the cuts and is therefore recommended for high performance RF resistors.

7.6. Combining Laser and Non-Laser Trimmed Resistors on One Substrate

As laser trimming is time consuming and therefore expensive, it is often desirable to have critical resistors laser trimmed to tight tolerances while leaving the rest of the resistors untrimmed. In order for both types of resistors to achieve design values, the process must be adjusted slightly.

1. Design non-trimmed resistors for 100% of the nominal sheet resistivity
2. Add a test resistor also designed to 100% of the nominal sheet resistivity
3. Design laser trimmed resistors for 90% of the nominal sheet resistivity ie design the resistors to be a bit larger than needed to accommodate the subsequent laser trim process.
4. After etching, the substrate will be heat treated until the test resistor is within 10% of its design value.
5. Critical resistors are then laser trimmed to their final value.

Example



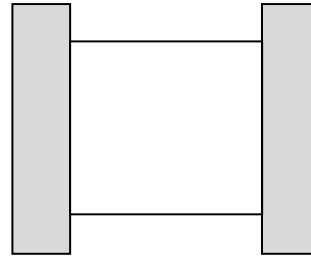
Non-Critical Resistor

Desired Value $50 \Omega \pm 10\%$
L = 50 W = 50

Before Heat Treating
Value = 45 Ω

After Heat Treating
Value = 50 Ω

After Laser Trim
Value = Unchanged



Critical Resistor

Desired Value $50 \Omega \pm 0.5\%$
L = 50 W = 55

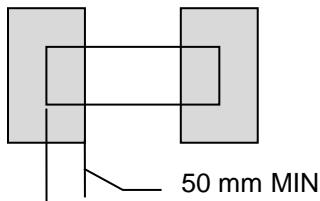
Before Heat Treating
Value = 40.9 Ω

After Heat Treating
Value = 45.9 Ω

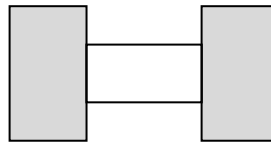
After Laser Trim
Value = $50 \Omega \pm 0.5\%$

9. Overlap of Resistors and Gold

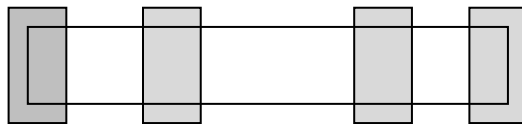
To avoid problems with small misalignment of the gold and resistor patterns, the resistor pattern on the resist mask should overlap the gold pattern by 0.05 mm minimum. Since this does not affect the final resistor in any way, overlap can be much bigger than 0.05 mm.



OK



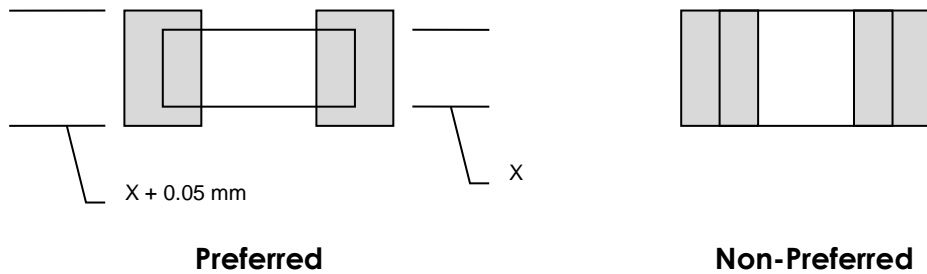
WRONG



OK

10. Gold Trace Larger than Resistor

To allow a margin for misalignment of resistors to conductor traces, it is preferred that the gold pads be 0.05 mm wider than the resistor.



11. Power Dissipation

No definitive studies have been performed to test the long-term reliability of the resistors built at Anritsu. Until these are performed we are using numbers that have been used commonly in the industry. Obviously, a lot of parameters will affect the power rating. If your circuit has poor heat sinking, tend to use the lower numbers; conversely, if you have a well heat sunk circuit, it is safer to use the higher numbers. The typical number, when applied to 25 mil micro strip circuits in a metal housing can be expected to change by less than 0.1% per year.

Most Conservative (MIL-SPEC for space applications)

50 Watts per square inch

Typical

400 Watts per square inch

Least Conservative

1200 Watts per square inch

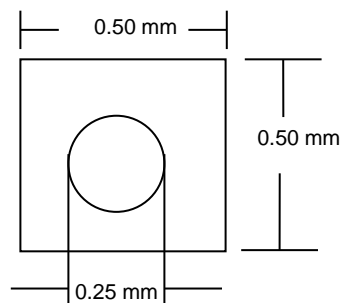
12. Vias, Slots and Laser Notch / Post Cut

12.1 Via Diameter

The standard via used at Anritsu is nominally 0.254 mm (.010") in diameter. The minimum via hole diameter that Anritsu is capable of doing is 0.152 (.006").

12.2 Pad Size for Vias

For etch back process, the edges of the conductor pad to the edges of the vias should be a minimum of 0.254 mm (0.005") via in all directions. For pattern plate process, smaller distance between the edges of the pad to the edge of the via can be as small as 0.076 mm (0.003").



12.3 Distance from Edge of Via to Edge of Circuit

Vias placed near the edge of circuits are prone to cracking problems. Therefore, leave at least 0.010" or one substrate thickness distance, whichever bigger, between the edge of a via and the edge of the circuit.

12.4 Distance between Vias

Vias placed close together are prone to cracking. Therefore, leave at least 0.010" or one time via diameter distance, whichever smaller, between via to via.

12.5 Vias in a Line

Many Vias in a line are prone to cracking. Try to avoid many vias in a line in your design.

12.6 Slots

MTC is capable of cutting different shape and sizes of slot and cut out, with or without metal. The minimum edge slot radius is .076 mm (.003"), which is the diameter of the laser beam itself. Consult MTC for feasibility.

13 Double Sided Circuits

Essentially, any circuit feature that can be realized on one side of a substrate can be realized on the back as well. It is easier if critical dimensions are limited to one side only. Circuits with complicated backside patterns should use polished substrate material.

13.1 Front to Back Alignment

The alignment accuracy from the front to the back of a substrate is +/- 5 μ m.

14 Step and Repeating and Alignment Marks

See MTC-DOC-02, the Guidelines for Mask Design for further information.

15 Integrated Capacitors

15.1 General

We can build integrated Polyimide, BCB or Silicon Nitride Capacitors. These materials are characterized by good mechanical properties, including fatigue resistance, excellent high temperature resistance or thermal stability, excellent chemical resistance and excellent electrical properties, particularly the dielectric strength. Polyimide and BCB are spin coated, photo patterned, and then thermally cured into a smooth, rigid, intractable polymeric film / structural layer. BCB capacitors have some advantages over Polyimide Capacitors, notably its low moisture absorption characteristics and lower cure temperatures. Silicon Nitride layer is deposited through a Plasma Enhanced Chemical Vapor Deposition (PECVD) process. PECVD SN layer is chemically inert, and have very low defect density.

15.2 Film Properties

The following are published film properties for Durimide 7500 and Cyclotene BCB 4024 which are currently stocked in the fab. Both materials can give films of about 2 μ m to 8 μ m in thickness. The Polyimide film is cured at 350 C for 1

hour, whereas the BCB film is cured at 250 C under a nitrogen atmosphere. PECVD SN is usually deposited in thickness from 1000 A to 2 um.

Material	Units	Polyimide (7500)	BCB (4024)	PECVD Silicon Nitride
Tensile Strength	Mpa	215	> 87	
Young's Modulus	Gpa	2.5	2.9	160
Tensile Elongation	%	85	8	
Thermal Decomposition Temperature	°C	525	>350	>400
Coefficient of Thermal Expansion	ppm/°C	55	42	
Coating Stress (100 Silicon)	Mpa	33	28	
Dielectric Constant 1 MHz; 0% / 50% RH		3.2 - 3.3	2.55 - 2.65	7
Dissipation Factor 1 MHz; 0% / 50% RH		0.0008 - 0.003	0.0008 – 0.002	
Dielectric Strength	V/μm	345	530	
Moisture Absorption @ 50% RH	%	1.08	0.075	
Density (cured film)	g/cc	1.39	1.05	3.05
Refractive Index @ 633 nm		1.69	1.56	2

15.3 Applications

In addition to the thin film capacitors, the dielectric materials above are also used for making overlay couplers, supported bridges and solder dams. For other possible types of application and design, please consult MTC personnel.

15.3.1 Capacitor

MTC thin film capacitor is in the pF range and has a breakdown voltage less than 100V. The Fab has a LCR measurement tool to measure any critical Caps. Polyimide unit capacitance is nominally 8 pF/mm² based on a dielectric constant of 3.2 and a film thickness of 4.0 μm. The tolerances will be +/- 10% depending on size. For critical applications, it is recommended that the final thickness and Cap values be physically measured and verified.

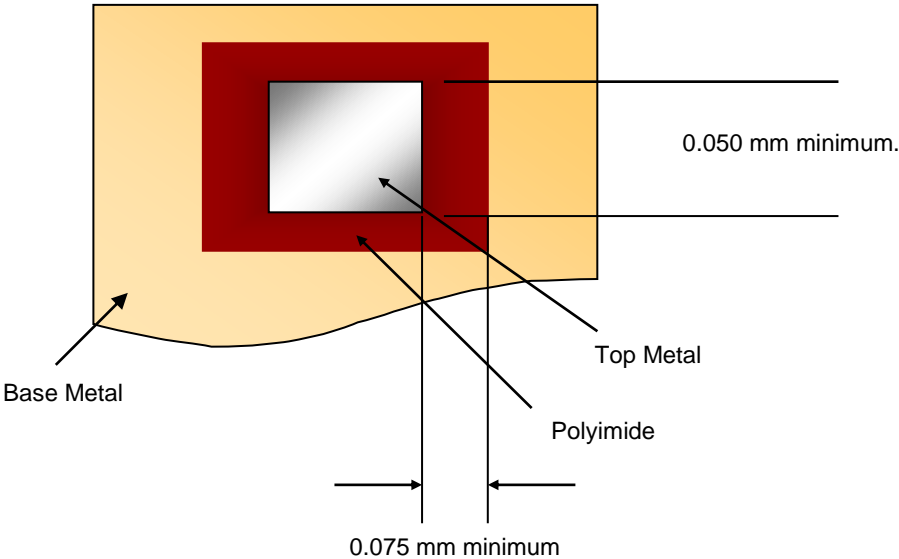
15.3.2 Top Metal

The top metal layer consists of sputtered Titanium Tungsten (50 nm) and electroplated gold (2.5μm).

15.3.3 Connection

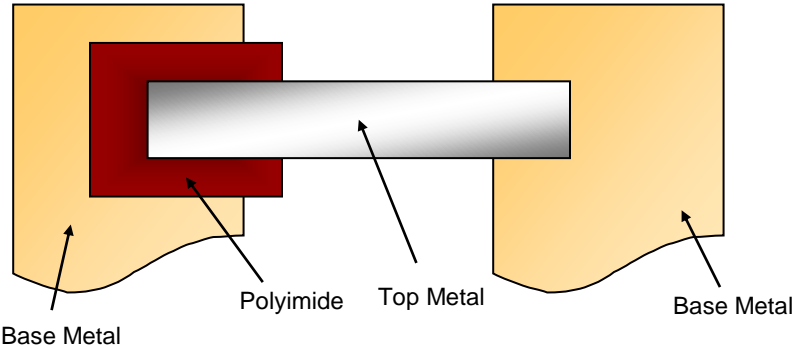
Connections can be made either by wire bonding or thin film connections. Minimum layout dimensions are shown below:

Capacitor Diagram Wire Bonding



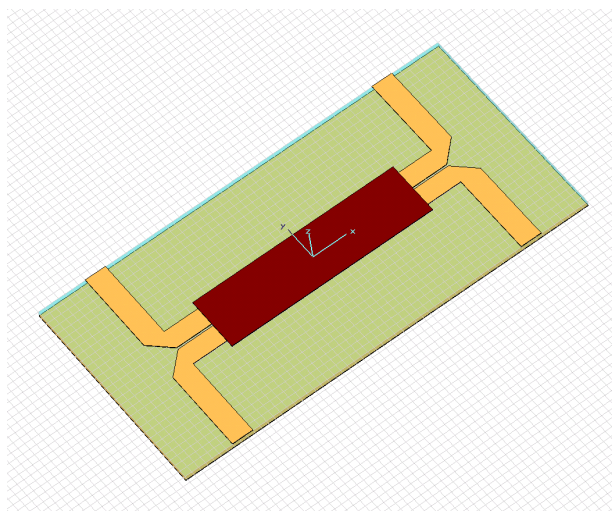
For wire bonding purposes, the minimum dimension for the top metal layer would be 0.1 mm x 0.1 mm. The distance from the polyimide edge to the top metal layer edge should be more than 0.075 mm. See above diagram.

Thin Film Interconnect



15.4. Overlay Couplers

A thin layer of polyimide is fabricated on the top of the two closely spaced parallel lines to increase the coupling factor. This type of coupler can be used as a substitute for Lange coupler, with the advantages of higher performance, more simplified design and less sensitivity with line width between the gap of the coupler.



15.4 Solder Dam

Various shapes of solder dams can be fabricated using polyimide. The purpose is to prevent the solder from flowing to unwanted areas. Polyimide has excellent chemical resistance, fluxes and cleaning solvents do not affect the cured polyimide. It also has excellent high temperature performance, thus it will withstand the 400°C reflow temperature. Sample layout can be seen as follows:

